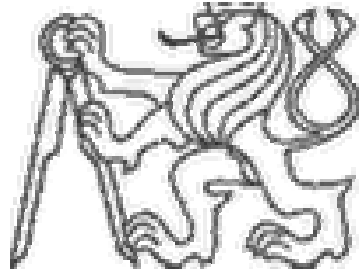


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GaAs PAD detector

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Motivation

The structure of detector on SI GaAs substrate
was created using:

- MOCVD epitaxy of PN junctions
- TiAu contact on P⁺ side
- alloyed AuGeNi contact on N⁺ side

This technology was developed to compare obtained results
with the diffused type of the precedent detectors

Structure of the detectors

SI GaAs substrate , thick. ~ 250 μm

MOCVD epi layer P⁺ (C) thickn. 0,3 μm , $\sim 8 \times 10^{18} \text{ cm}^{-3}$

MOCVD epi layer N⁺ (Si) – back side, 0,4 μm , $\sim 8 \times 10^{18} \text{ cm}^{-3}$

Metallization of P⁺ : TiAu (10 + 200) nm

Metallization of N⁺ : AuGeNi (200+100+100) nm, alloyed
at 400°C in forming gas

Technology for GaAs detectors

MOCVD type with guard ring

deposition of MOCVD epi layer (P⁺, dot. C)

back side deposition of MOCVD epi layer (N⁺, dot. Si)

making a ohmic contacts on P⁺ and N⁺ side of structure

- P⁺ side metallization : TiAu

- N⁺ side metallization : AuGeNi

etching of the metallization to designed pattern following etching of GaAs (patterned metallization serves as etching mask) to form MESA structure without need of additional passivation

Structure of the detectors

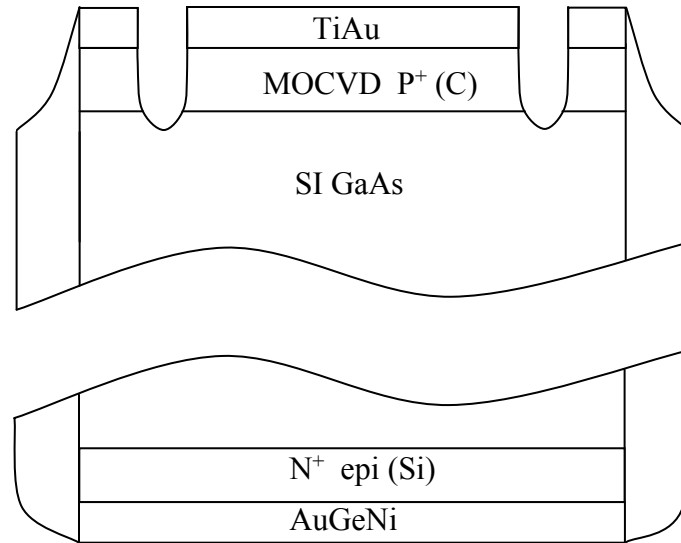


Fig.1: Vertical structure of detector with guard ring - MOCVD epi type of structure

Results

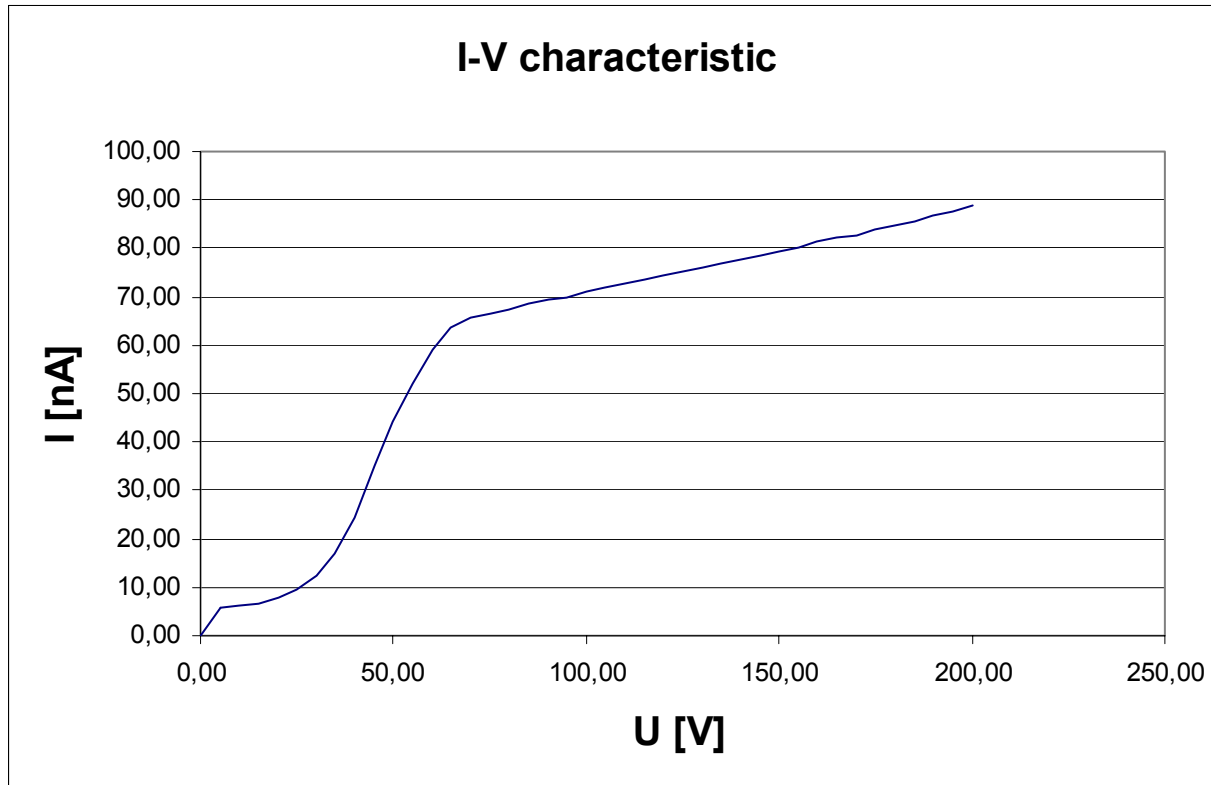


Fig. 2: I-V characteristic of GaAs PAD (MOCVD)

Results

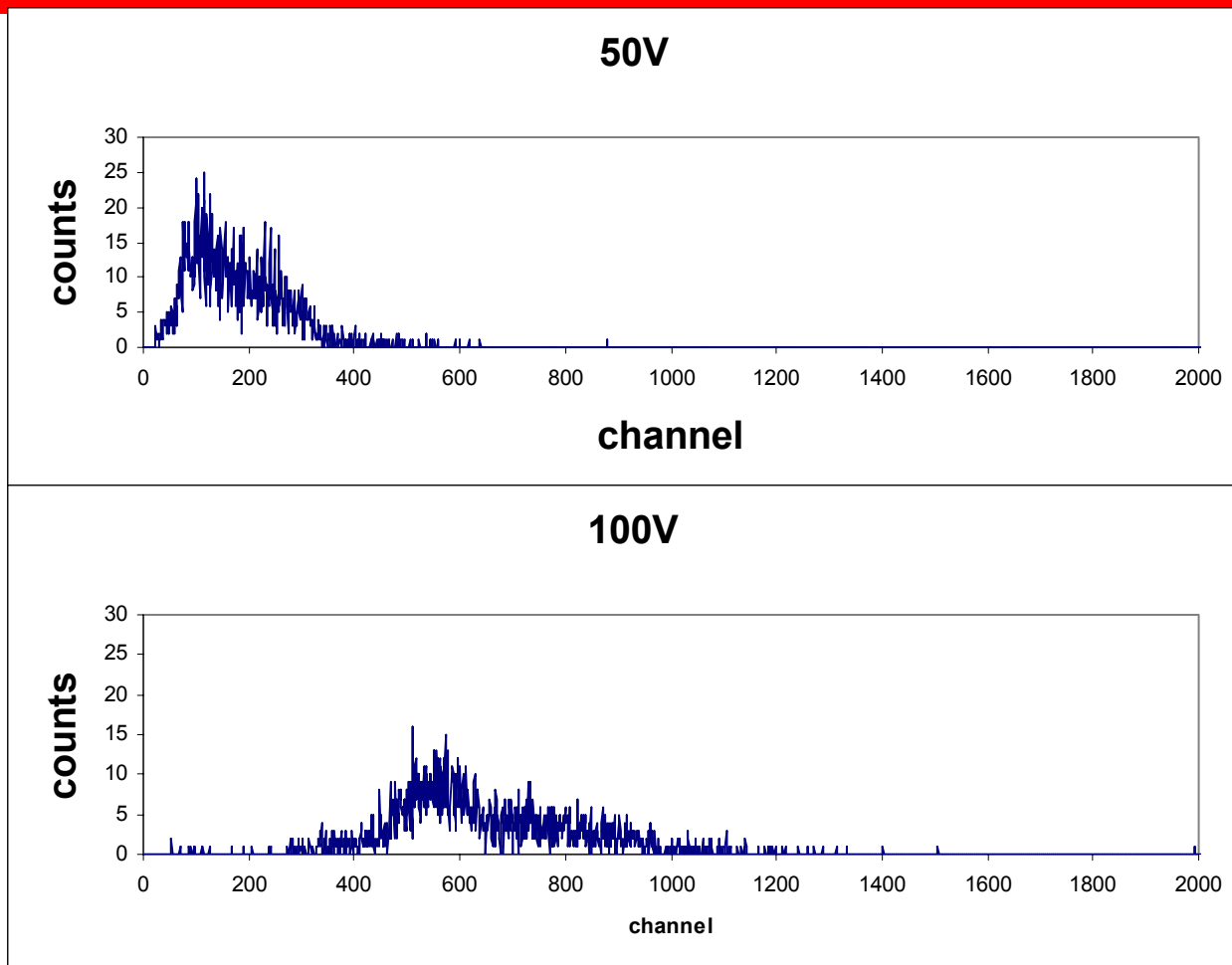


Fig. 3: Alpha response

Results

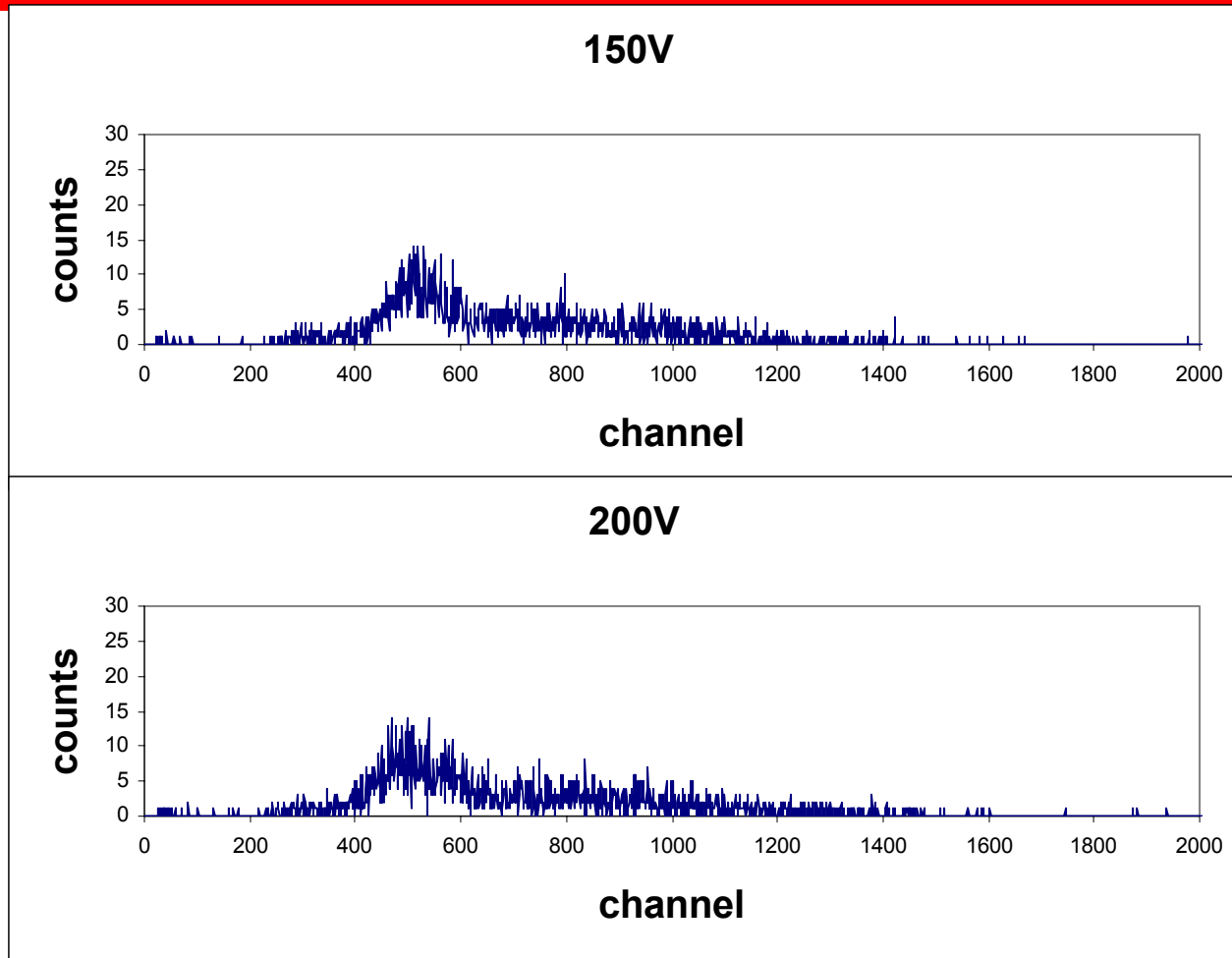


Fig.: 4 - continuation (All presented spectra were measured using alpha-particle source $\text{Am}^{241}\text{Pu}^{239}$)

Results

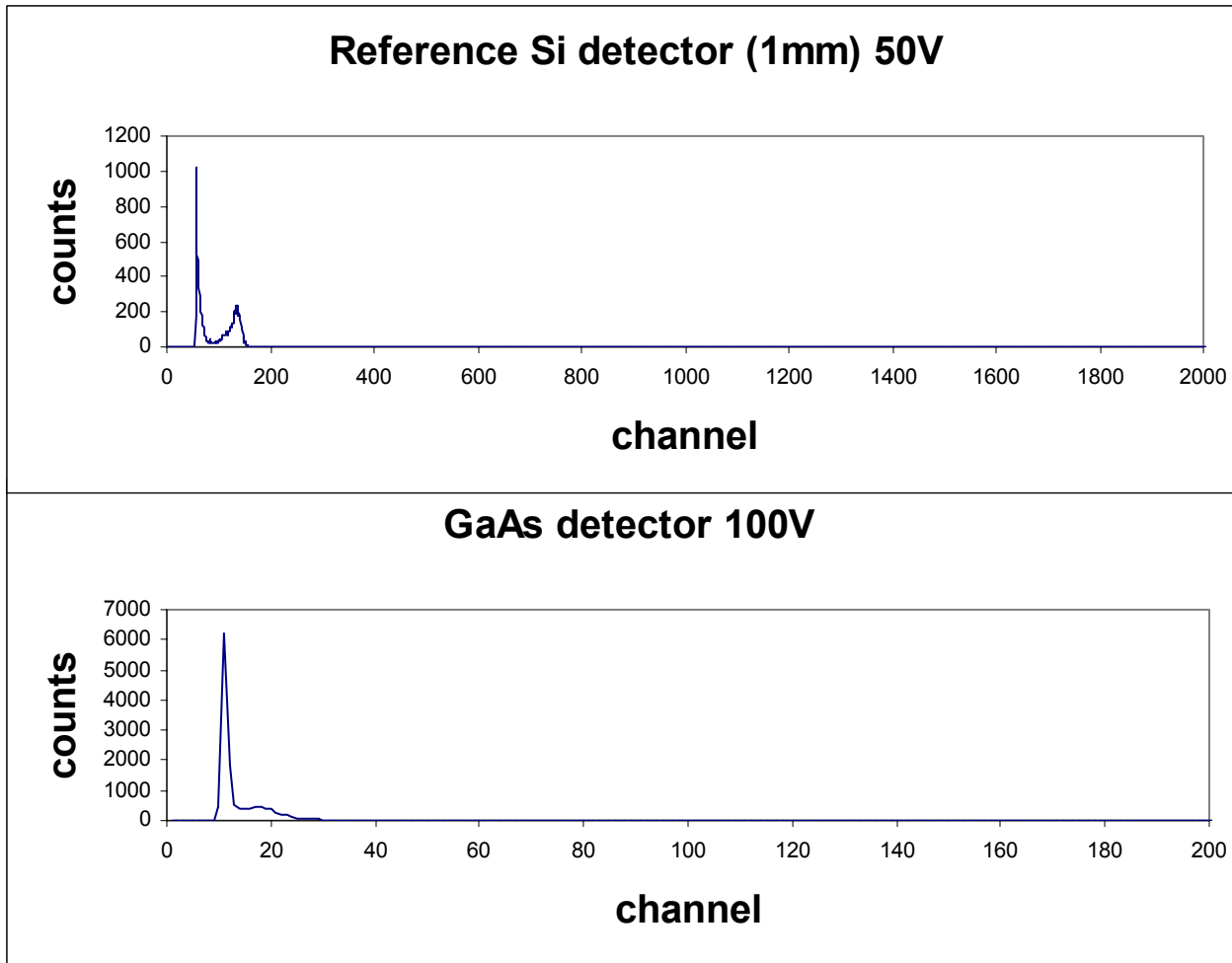


Fig. 5: Gamma response

Results

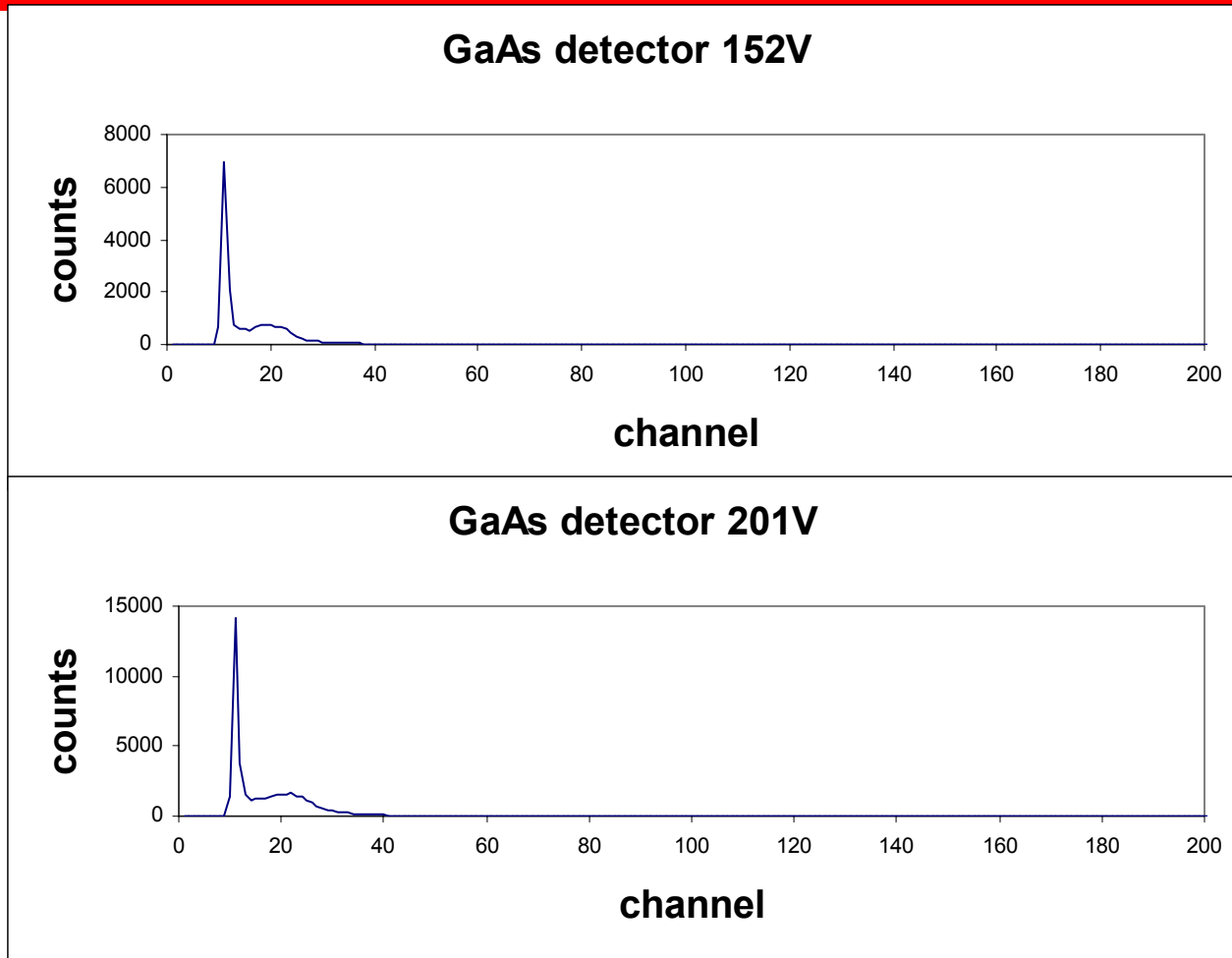


Fig. 6: Gamma response - continuation

Results

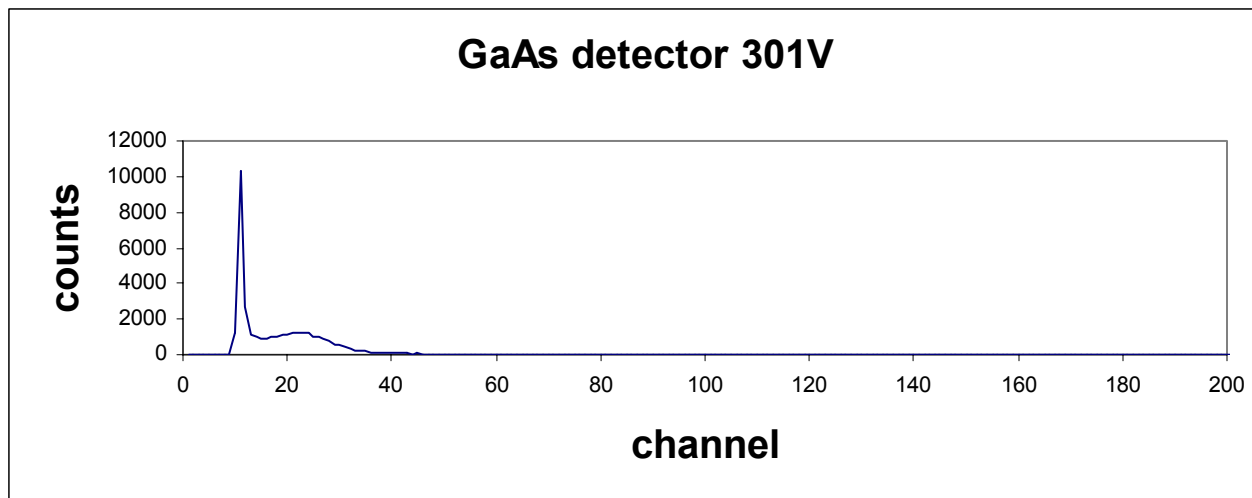


Fig. 7: Gamma response - continuation

Conclusions

- Experiments show the ability of described technology to prepare functional detectors on GaAs
- The CCE is lower in comparison with the Si type
- The GaAs detectors show better sensitivity for photons
- In near future will be measured the response for X- rays

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Thank you for your attention